

AMENDMENTS TO THE CLAIMS

Please amend the claims as follows:

1. (Currently Amended) A pressure sensor comprising: plural first wires and plural second wires intersecting with each other in arrangement; and sensor sections provided in the vicinities of the respective corresponding intersections, wherein

each of the sensor sections includes:

a first electrode electrically connected to the first wire;

a second electrode disposed opposite to the first electrode; and

a cavity formed between the first electrode and the second electrode, and

the second ~~first~~ wires ~~work additionally as the second electrodes in~~ have larger width portions in spaces between adjacent sensor sections and narrower width portions in the vicinities of the sensor sections, and

the narrower portions have outlines that are at a substantially constant spacing from outlines of the respective sensor sections.

2. (Currently Amended) The pressure sensor according to claim 1, wherein
the first ~~second~~ wires ~~have larger width portions in respective spaces between adjacent~~ work additionally as the second electrodes in the sensor sections.

3. (Canceled)

4. (Currently Amended) The pressure sensor according to claim ~~[[2]]~~1, wherein

the first wires are connected to the first electrodes at the larger width portions.

5. (Previously Presented) The pressure sensor according to claim 1, wherein all of the first wires and all of the second wires extend outwardly from the outermost peripheral boundary portion where sensor sections along the outermost periphery are disposed.
6. (Original) The pressure sensor according to claim 5, wherein all of the first wires and all of the second wires extend outwardly from the outermost peripheral boundary portion by a length of 100 μm or more.
7. (Previously Presented) The pressure sensor according to claim 1, wherein dummy sensor sections are disposed in the outermost peripheral portion of a region including the sensor sections.
8. (Previously Presented) The pressure sensor according to claim 1, wherein the first wires are connected to the first electrodes through contact layers higher in resistance than the first wires.
9. (Original) The pressure sensor according to claim 8, wherein the contact layers are formed with a silicon layer mixed with a conductive impurity.

10. (Original) The pressure sensor according to claim 8, wherein the contact layers are formed with polycrystalline silicon.
11. (Previously Presented) The pressure sensor according to claim 1, wherein the first wires are connected to the first electrodes through switching elements.
12. (Original) The pressure sensor according to claim 11, wherein the switching elements are thin film transistors.
13. (Previously Presented) The pressure sensor according to claim 1, wherein a scanning signal is sequentially supplied onto the plural first wires.
14. (New) The pressure sensor according to claim 1, wherein the narrower portions have substantially arc-shaped outlines along outlines of the first electrodes.